

	2025				DISU221		01
							0-3-1
	(09:00 ~ 18:00) -						
E-Mail	BCLEE@POSTECH.AC.KR			Homepage			
					054-279-5079		
Office Hours							
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Coater, Developer, Exposure #

E-Beam Lithography #

Mask Aligner #

ICP Etcher #

Etching on pattern depth #

PR asher 02Plasma #

Ashing #

Furnace #

RTP #

PVD #

PE-CVD SiO2 #

LP-CVD Poly si #

ALD AL2O3

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